



#5 FDS  
Townsend  
PATENT APPLICATION  
08/16/02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of

Akihiro OSAKA et al.

Application No.: 10/073,876

Group Art Unit: 3651

Filed: February 14, 2002

Docket No.: 105913.01

For: SEMICONDUCTOR MANUFACTURING METHOD AND SEMICONDUCTOR  
MANUFACTURING APPARATUS

INFORMATION DISCLOSURE STATEMENT

Director of the U.S. Patent and Trademark Office  
Washington, D.C. 20231

Sir:

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Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. The references were cited in a counterpart foreign application. An English language version of the foreign Office Action is attached for the Examiner's information.

Respectfully submitted,

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JAO:HNS/cfr

Date: August 12, 2002

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